IN THE ABSTRACT

Please amend the Abstract of the Disclosure as follows:

A method of fabricating a single crystal thin film includes the steps of: forming a nonsingle crystal thin film on an insulating base; subjecting the non-single crystal thin film to a first
heat-treatment, thereby forming a polycrystalline thin film in which polycrystalline grains are
aligned in an approximately regular pattern; and subjecting the polycrystalline thin film to a
second heat-treatment, thereby forming a single crystal thin film in which the polycrystalline
grains are bonded to each other. In this method, either the first heat-treatment or the second
heat-treatment may be performed by irradiation of laser beams, preferably, emitted from an
excimer laser. A single crystal thin film formed by this fabrication method has a performance
very higher than a related art polycrystalline thin film and is suitable for fabricating a device
having stable characteristics. The single crystal thin film can be fabricated for a short-time by
using laser irradiation as the heat-treatments.